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a plurality of metal posts formed on the electrode pads of the redistribution layer, the metal posts being configured to be provided with external connection electrodes; and

at least one mark member which serves as an alignment mark located in a predetermined positional relationship with the metal posts,

wherein the mark member is made of the same material as the metal posts.

- 2. The semiconductor device as claimed in claim 1, wherein the alignment mark has an outer configuration other than a circle.
- 3. The semiconductor device as claimed in claim 1, wherein a width of the alignment mark measured along a plane parallel to a surface of the redistribution layer is greater than a height of the metal posts.
 - 4. A semiconductor device comprising:
 - a semiconductor element having a plurality of electrodes;
- a redistribution layer which connects the electrodes of the semiconductor device to electrode pads located in predetermined positions of the redistribution layer; and
- at least one mark member which serves as an alignment mark located in a predetermined positional relationship with the electrode pads, wherein the mark member is made of the same material with the electrode pads.

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5. The semiconductor device as claimed in claim 4, wherein the alignment mark has an outer configuration other than a circle.

13. (Three-times Amended) An apparatus for fixing a semiconductor wafer by suction, comprising:

a vacuum chuck table having a porous plate overlaying a plurality of concentric suction grooves;

a plurality of suction passages being connected to the plurality of concentric suction grooves, the plurality of concentric suction grooves being divided into a plurality of groups so that each of the plurality of suction passages is connected to one of a corresponding suction grooves belonging to one of the plurality of groups; and

means for sequentially introducing a suctioning force into the suction passages at different timing.